

What is claimed is:

1. A probe apparatus comprising:
a mounting member on which an object to be inspected
5 is mounted, a temperature of the object being adjusted by
the mounting member;
a probe card arranged opposite to the mounting member;
a driving mechanism which changes the relative
positional relationship between the mounting member and the
10 probe card; and
a sensor which detects the distance between the sensor
and the probe card.
2. The probe apparatus of claim 1, wherein the sensor is
15 a laser displacement sensor or a capacitive sensor.
3. The probe apparatus of claim 1, wherein the driving
mechanism moves the mounting member in X, Y and Z directions.
- 20 4. The probe apparatus of claim 1, wherein the sensor is
attached to the driving mechanism.
5. The probe apparatus of claim 4, wherein the sensor is
a laser displacement sensor or a capacitive sensor.
- 25 6. The probe apparatus of claim 4, wherein the driving

mechanism moves the mounting member in X, Y and Z directions.

7. The probe apparatus of claim 1, wherein the sensor is provided at a part of the apparatus to which the probe card
5 is fixed.

8. The probe apparatus of claim 7, wherein the sensor is a laser displacement sensor or a capacitive sensor.

10 9. The probe apparatus of claim 7, wherein the driving mechanism moves the mounting member in X, Y and Z directions.

10. The probe apparatus of claim 1, wherein the sensor is installed on the mounting member.
15

11. The probe apparatus of claim 10, wherein the sensor is a laser displacement sensor or a capacitive sensor.

12. The probe apparatus of claim 10, wherein the driving
20 mechanism moves the mounting member in X, Y and Z directions.

25